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Microfabricated cells for chip-scale atomic clock based on coherent population trapping: Fabrication and investigation

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Abstract

A universal method for fabrication of miniature cells for frequency standards and quantum magnetometers containing ^{87}Rb atoms in the atmosphere of inert gas neon based on integrated technologies is considered. The results of experimental studies of coherent population trapping signals observed for a series of cells which provided recovery of vapors of an alkali metal from the rubidium dichromate salt with the help of laser radiation are presented. The coherent population trapping signals with a typical linewidth of 2–3 kHz and a signal-to-noise ratio of 1500 in the 1-Hz bandwidth were observed, which allows one to provide a relative frequency stability of atomic clock of 10^{-11} at 100 s.

Keywords: Laser spectroscopy; Coherent population trapping; MEMS technology; Microfabricated cell; Alkali atom; Quantum frequency standard.

1. Introduction

A growing interest in small-size telecommunications systems having various applications has brought significant advances in development of miniature quantum devices to which chip-scale atomic clocks (CSACs) and chip-scale quantum magnetometers (CSQMs) belong. Miniature CSACs are used to synchronize the operation of electronic devices and to set a precise time in portable applications where a small size, a low power consumption, a good long-term stability, and resistance to considerable mechanical perturbations are important [1]. Small-size CSQMs in the form of compact matrix-type sensors find application in a variety of biomagnetic studies [2]. Basic elements of miniature CSACs and CSQMs are a laser source (single-mode vertical-cavity surface-emitting laser VCSEL) and a cell that contains alkali metal atoms (typically ^{87}Rb, ^{85}Rb, ^{133}Cs) in a buffer gas atmosphere. The cell quality strongly depends on the amount of alkali metal, the buffer gas pressure and composition, and the presence of impurities in the cell and directly affects the stability and reproducibility of the CSAC and CSQM characteristics. The

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most appropriate technology that can ensure a high quality of cells for such devices is the microelectromechanical systems (MEMS) manufacturing technology. It combines the advantages offered by the techniques of microelectronic component fabrication and manufacturing and assembling miniature mechanical systems [3]. The great importance for miniature CSACs and CSQMs design have the method of a resonance signal inducing for comparison an atom transition frequency with the frequency of the reference oscillator. Classical analogs of precision quantum devices use the method of double radio–optical resonance (DROR) [4,5]. The use of the microwave volume resonators hinders for the device miniaturization. In this case, the effect of coherent population trapping (CPT) is extremely attractive because it does not require the use of microwave resonators and ensures the formation of a sufficiently reliable resonance signal under the conditions of interaction between the working substance atoms and the optical field of the pump laser [6,7].

2. Method for cells manufacturing

For the studies, cells with a universal construction (Fig. 1) were fabricated. The microfabricated cells were designed so that they could be included into the optical path in two ways: in the transmission mode for the cells with a thickness more than 1 mm (Fig. 2a) [8,9] or with a double reflection of the pump beam from inner walls of the cells with a submillimeter thickness

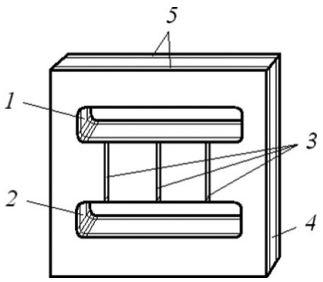

Fig. 1. Microfabricated cell: *1*, *2* – working and additional cavity, respectively, *3* – connecting channels, *4*, *5* – silicon and glass plates, respectively.

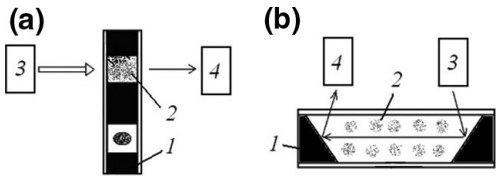

Fig. 2. Cell (*1*) incorporation into the optical path: pump beam is transmitted through the cavity (a), pump beam passes along the channel with reflections (b), *2* – working cavity, *3* – laser, *4* – photoreceiver.

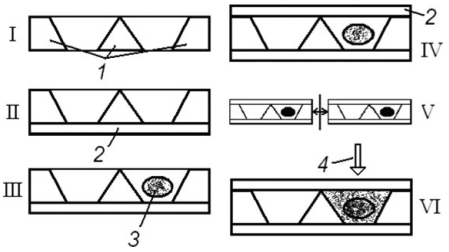

Fig. 3. Stages of cell fabrication: I – alkaline etching of silicon; II, IV – bonding of the first and second glass plates; III – placing titanium mini-tablet with rubidium dichromate; V – separation into chips; VI – laser activation; *1* – silicon, *2* – glass, *3* – rubidium dichromate, *4* – laser beam.

(Fig. 2b) [1]. The additional cavity 2 (see Fig. 1) was necessitated by the use of the method of recovery of an alkali metal from the rubidium dichromate salt including interaction of a material with an activating laser radiation [10]. Channels 3 (see Fig. 1) provided, due to a small cross-section, a transfer of rubidium atoms into the working cavity without byproducts formed during recovery of alkali vapors.

Fig. 3 shows schematically a simultaneous fabrication of 97 cells. At the first stage (I) of the technological process, cavities were etched by a deep alkaline etching through the entire thickness of the KEF-20 silicon wafer with the (100) orientation. The etching was carried out in a 30% aqueous solution of potassium hydroxide during 8 h at 80 °C. At the second stage (II), a flat glass plate (LK5 glass) was attached to the bottom side of the silicon wafer by using anodic bonding in air at 450 °C under a voltage of 800 V for 30 min. At the third stage (III), a titanium mini-tablet containing a few percent of rubidium dichromate about 200 μm in diameter was placed into each of the 97 cells by using a special mask. At the fourth stage (IV), the second glass plate was attached to the upper side of the silicon wafer by anodic bonding. Bonding was performed in a neon atmosphere (under a pressure of 200 mmHg) during 2 h at 400 °C, under a voltage of 350 V. Prior to bonding, all elements were outgassed under vacuum (under pressure of 10^{-4} mmHg) at 450 °C for an hour. At the fifth stage (V), the three-layer structure (glass–silicon–glass) was separated into chips by a diamond cutting disk. At the sixth stage (VI), each tablet was activated by an IR laser.

3. Investigation of cell characteristics

To study experimentally the small-size cells prepared by the procedure described above, the setup presented schematically in Fig. 4 was used. A laser beam (L) was